

## Hitachi High Technologies America, Inc.

Hitachi High Technologies America, Inc. (HTA) provides technologically advanced solutions to meet the diverse and complex challenges of materials science, biological research, and industrial manufacturing. HTA supports our satisfied customers with a wide range of reliability-proven instrumentation, including scanning electron microscopy (SEM), analytical and biological transmission electron microscopy (TEM), dedicated STEM, focused ion beam (FIB), tabletop SEM microscopes, and microanalysis sample preparation systems.

As a pioneer in variable-pressure SEM, Hitachi proudly launched our latest “premium class” VP-SEM, the SU3500. The innovative SU3500, with real-time 3D imaging, is the culmination of more than 40 years of SEM technology development and commercial manufacturing.

### SU1510, S-3400, S-3700, SU3500 (VP-SEM)

- A wide range of Variable-Pressure SEMs with proprietary Quad/Hex bias for unmatched low kV and low vacuum performance.
- Real-time 3D imaging (SU3500).

### SU70, SU6600 (SEM)

- Analytical SEMs with Advanced Schottky electron gun technology combined with our exclusive ADAPT, automated differential aperture system, for increased current.
- Versatile analytical chamber/port designs for accommodating EDX, WDX, EBSP, STEM, BSE, and CL.

### SU8000 Series (SEM)

- Ultra-high performance, semi-in-lens SEM with cold-field emission.
- Hitachi’s patented super ExB in-lens detection for energy filtering, charge suppression, and contrast control—affording ultra-low voltage imaging resolution of 1.3 nm at 1.0 kV.

### SU9000 Series (UHR-SEM)

- Ultra-high resolution SEM: true in-lens design combined with the next generation of Hitachi’s cold field emission technology—guarantees the highest possible system resolution (0.4 nm @ 30 kV, 1.2 nm @ 1 kV) and stability.

### HT7700 (Bio-TEM)

- The HT7700 with EXALENS high resolution objective lens sets the new performance standard for 40–120 kV microscopy – 1.4 Å at low accelerating voltages with minimal beam damage.

### HD-2700 (STEM)

- The incomparable HD-2700 dedicated STEM features the Hitachi developed spherical aberration correction system affording unmatched resolution, analytical sensitivity, and throughput.

### NB5000 NanoDUE’T (FIB-SEM)

- The NanoDUE’T integrates a superior 40 kV Ga ion FIB column with an ultra-high-resolution Schottky FE-SEM.

### IM4000 (ion milling)

- Flat Ion Milling and Cross Section Milling in one instrument.

### Zone Systems (sample cleaning)

- The next generation, nondestructive cleaning technology offering an easy-to-use solution that ensures the best possible images and data from your TEM or SEM samples.

### TM3000 (Tabletop SEM)

- Hitachi’s latest tabletop SEM provides variable accelerating voltage, higher beam current, large stage/chamber, and smaller footprint for unmatched performance and image quality.

**HITACHI**  
Inspire the Next



## How to find us

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